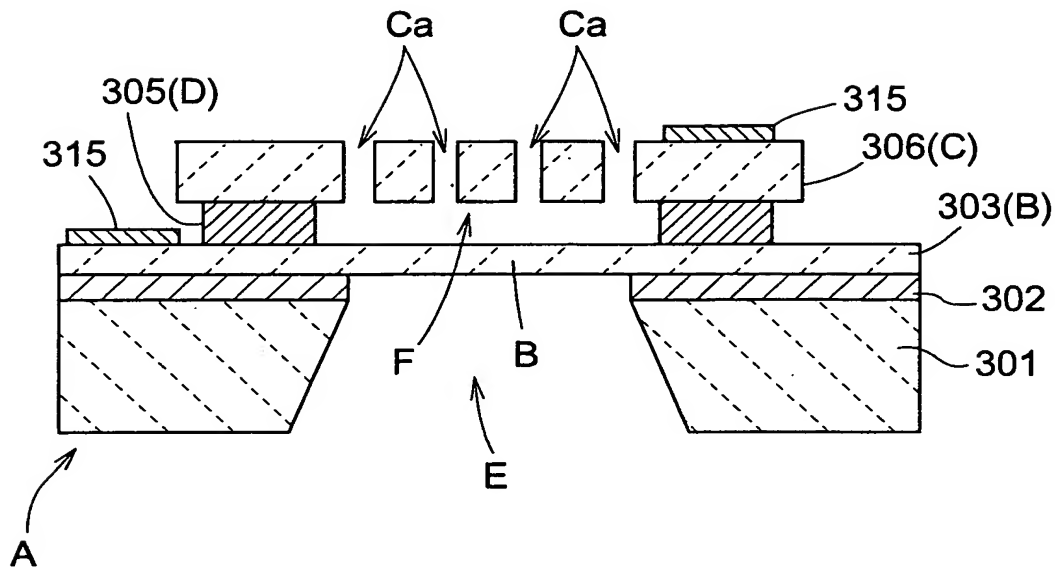


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FIG.1



A: support substrate

B: diaphragm

C: back electrode

D: spacer

E: acoustic opening

F: void area

301: monocrystal silicon substrate

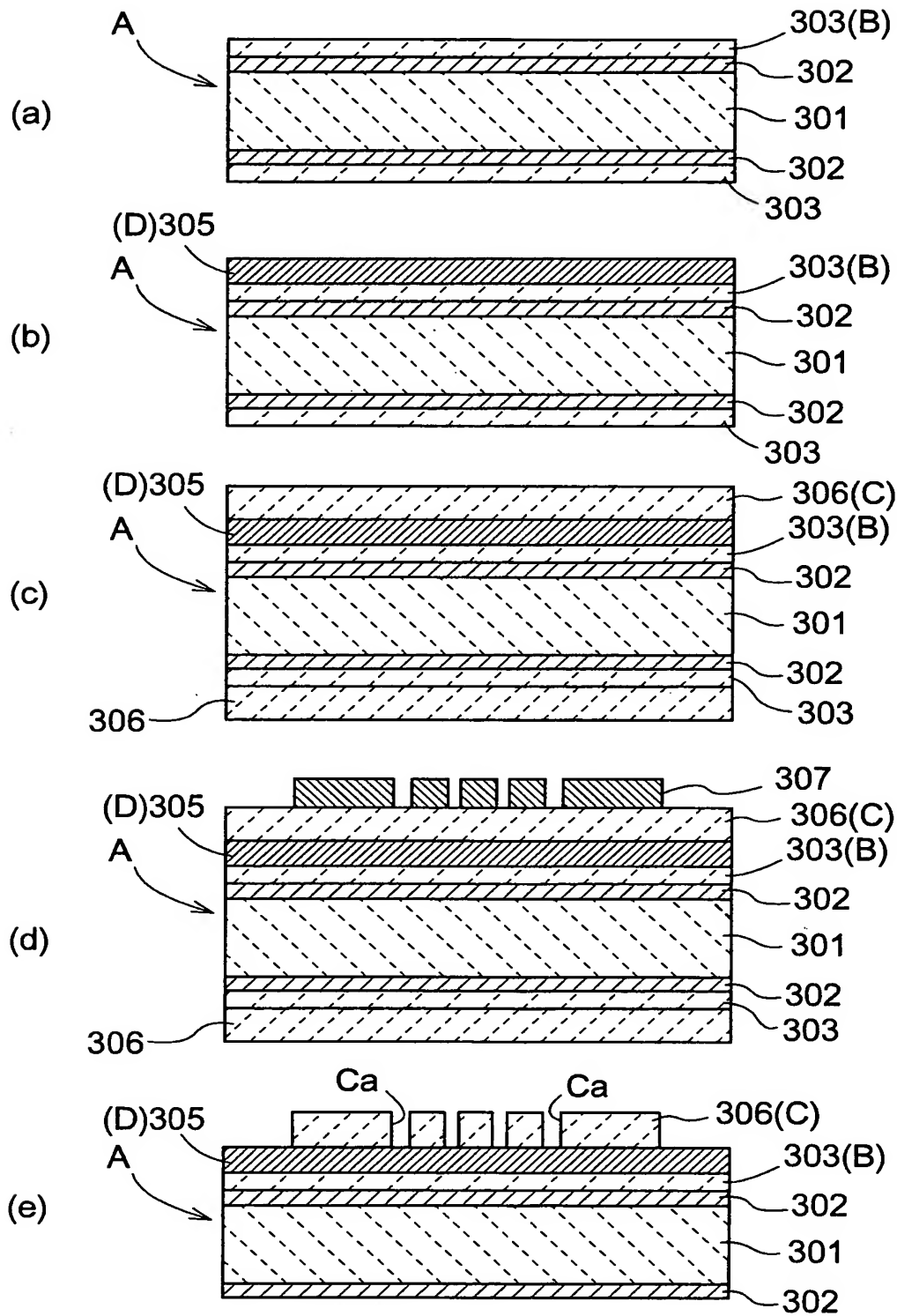
302: silicon oxide film

303: polycrystal silicon film

305: sacrificial layer

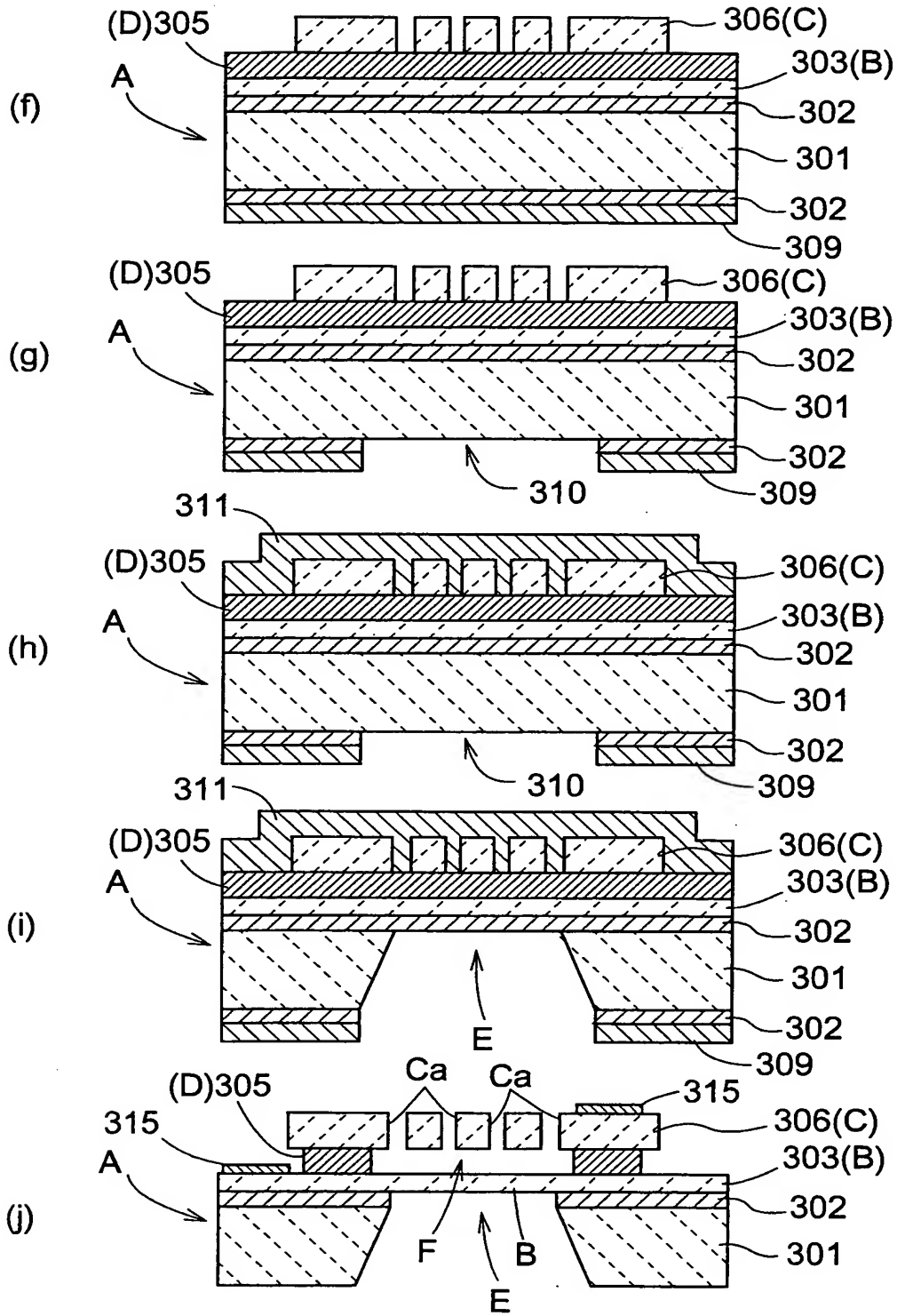
306: polycrystal silicon film

315: take-out electrode

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FIG.2

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FIG.3



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FIG.4

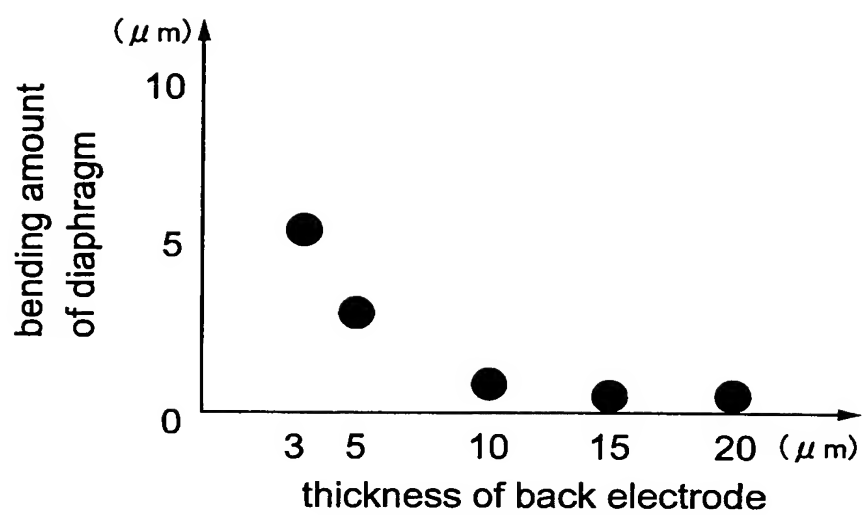
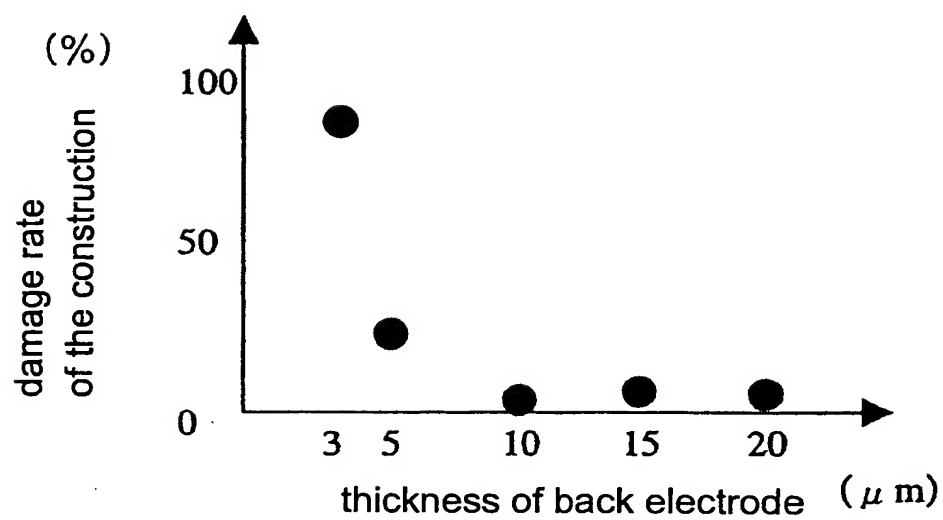


FIG.5



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FIG.6

